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Development of High Voltage High Frequency Resonant Inverter Power Supply for Atmospheric Surface Glow Barrier Discharges Inactivation and Destruction of Bacillus Subtilis Using a Low Pressure Glow Discharge Plasma; Efficiency of Energy Transfer in a Small Plasma Focus Device; Sterilization Performance of Ultraviolet Emission from Laser Plasmas; Formation and Characteristics of the Low Dielectric Carbon Doped Silicon Oxide Thin Film Deposited by MTMS/O₂ - ICPCVD; Ion Beam Modification of Carbon Materials
Anti-Corrosion Properties of Nitrogen and Oxygen Plasma-Implanted Nickel-Titanium Shape Memory Alloy Structural and Conductive Changes of Alumina Ceramics and Silicon Crystal Implanted with High-Flux Ti Ion; Atmospheric Pressure Plasma Jets for 2D and 3D Materials Processing; Plasma Treatment of Silk; Diamond-Like Carbon Formed by Plasma Immersion Ion Implantation and Deposition Technique on 304 Stainless Steel; Tribological Improvement of Thermal-Sprayed Ti-Based Coatings Modified by 1200 K Nitridation; Thermal Stability of Nanoscale Multilayered ZrAlN/ZrB₂ Coatings
Improve Stability of Dicalcium Silicate/Zirconia Composite Coatings by Post-Spraying Heat Treatment Deposition of TiC on -TiAl Alloys by Directly Applying Voltages; Generation of Deuteron Beam from the Plasma Focus; Keywords Index; Authors Index

Sommario/riassunto

This collection presents, and analyses, the new ideas in the emerging technologies involved in the production and use of particle beams and plasmas. Another object of the work is to offer the opportunity to exchange knowledge and information concerning recent advances in, and the future directions of, the fields of surface modification and material synthesis by ion-beam and plasma processing. Among the exciting topics covered are: Novel technologies for the production and utilization of particle beams and plasma; Characterization of particle beams and plasma; Basics and applications of beam in
